



Inverted trinocular LED fluorescence microscope, B, G & UV filter set, IOS

Observation Method - Transmitted Light	Brightfield	Yes
	Phase contrast (Positive type)	Yes
	Darkfield	Yes
Observation Method - Incident Light	Fluorescence	Yes
U		
Main Body	Туре	Inverted
	Construction material	Aluminum die-cast
Head	Туре	Trinocular (Siedentopf)
	Split ratio	100/0 - 0/100
	Inclination	45°
	Interpupillary distance (mm)	50-75
	Fixing screw for eyepieces	Yes
Eyepieces	Field number (mm)	24
	Magnification	10x
	Planar type	Yes
	Micrometric scale	As optional
	Diameter of micrometer glass (mm)	26
	High eyepoint (for glass wearers)	Yes
	Dioptric adjustement	Yes
	Rubber cup	Yes
	Retractable protections	Yes
Nosepiece	Positions	Quintuple
	Reversed	Yes
	Bi-directional	Yes
	Rotation on ball bearings	Yes
	Objective thread	RMS
	Objective thread	TWO
Objectives	Optical system	×
Objectives	Anti-fungus treatment	Yes
	Parfocal distance (mm) Standard magnifications	45 40x-600x
	Configurable objectives	IOS LWD W-PLAN 4x/0.13, W.D. 10.4 mm
		IOS LWD W-PLAN
		40x/0.60, W.D. 3.1 mm
		IOS LWD W-PLAN

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	IOS LVD W-FLAN
	60x/0.70, W.D. 1.7 mm
	IOS LWD W-PLAN PH
	4x/0.13, W.D. 10.4 mm
	IOS LWD W-PLAN PH
	10x/0.25, W.D. 7.3 mm
	IOS LWD W-PLAN PH
	20x/0.40, W.D. 6.8 mm
	IOS LWD W-PLAN PH
	40x/0.65, W.D. 3 mm
	IOS LWD U-PLAN F
	4x/0.13, W.D. 18.52 mm
	IOS LWD U-PLAN F
	10x/0.30, W.D. 7.11 mm
	IOS LWD U-PLAN F
	20x/0.45, W.D. 5.91 mm
	IOS LWD U-PLAN F
	40x/0.65, W.D. 1.61 mm
	IOS LWD U-PLAN F
	60x/0.75, W.D. 1.04 mm
	IOS LWD U-PLAN F PH
	20x/0.45, W.D. 5.91 mm
	IOS LWD U-PLAN F PH
	40x/0.65, W.D. 1.61 mm

Stage Type Fixed + Attachable mechanical stage Dimensions (mm) 215x250 (fixed stage) Qaya250 (with mechanical stage mounted) Moving mechanism Rack and pinion Moving range (mm) 120x80 Material Anti-scratch painting Glass round insert Yes Holder for Petri dish (mm) 38, 54, 65 Holder for Terasaki plate 96 well Holder for 1 slide Yes Numerical aperture (N.A.) 0.50 Diaphragms Iris Slider for phase contrast BF, 4x/10x, 20x/40x positions Slider for darkfield (dry) Yes Long working distance Yes Working distance Yes Working distance (for LWD) (mm) 28 Extendable working distance (for LWD) (mm) 220 Centrable By rack and pinion	
Focusing System Type Abbe Resonance (for LWD) (mm) 0.50 Diagrams Brite Sider for darkfield (dry) Yes Contained (dry) 0.50 Position Sider for Contained (dry) Processing System Type Focusing System Type Type Converse & fine Fine resolution (mm) 28 Extendable working distance Yes Holder for T strast Strate (dry) Position Type Abbe Removable Yes Numerical aperture (N.A.) Diaphragms Iris Silder for darkfield (dry) Yes Long working distance Yes Working distance (for LWD) (mm) 28 Extendable working distance (for LWD) (mm) Yes Focusable Strate and pinion	
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Upper stop to prevent contact Yes	
Adjustable tension Yes	
Transmitted Kohler illumination Full	
Illumination Type X-LED	
X-LED type X-LED8	
Light source power (W) 8	
Brightness control Manual	
Lifetime (hours) > 65,000	
Temperature (K) 6,300	
Max. required power (W) 13	
Dower Supply for Type	
Power Supply for Type External Transmitted Microscope connector Jack 21 mm	
Input voltage 100/240 Vac, 50/60 Hz	
Output voltage 12 Vdc 5 A	
ECO function Yes	
LED indicator Yes	
Accessories Included Dust cover Yes	
Allen wrench Yes	
Centering telescope Yes	
Green filter Yes	
LBD filter Yes	
User Manual Digital version (downloadable)	

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Product Dimensions	Height (mm)	545
	Width (mm)	290
	Depth (mm)	720
Product Weight	(kg)	13
Fluorescence	Number of positions	4
Attachment	Blue filter set (included) specs	Excitation: 450 - 490 nm; Dichroic: 495 nm;
		Emission: 500 - 550 nm
	Green filter set (included) specs	Excitation: 540 - 580 nm; Dichroic: 585 nm;
		Emission: 608 - 682 nm
	UV filter set (included) specs	Excitation: 340 - 390 nm; Dichroic: 400 nm;
		Emission: 420LP nm
	Filter dimensions	Excitation: 25 mm diam.;
		Dichroic: 36 mm x 25 mm;
		Emission: 25 mm diam.
	Filter set selection	Manual
	LED source insertion	Motorized
	Field diaphragm	Centerable
Fluorescence Light Source	Light source	Blue - Green - UV LEDs
		Optional LED on request
	Watt (W)	5
		Blue LED: 470 nm
	LED wavelength	Green LED: 560 nm
		UV LED: 385 nm
	Lifetime (hours)	> 65,000
	Brightness control	Yes

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Pricing on any accessories shown can be found by keying the part number into the search box on our website. The specifications listed in this brochure are subject to change by the manufacturer and therefore cannot be guaranteed to be correct. If there are aspects of the specification that must be guaranteed, please provide these to our sales team so that details can be confirmed.

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Please contact us if this literature doesn't answer all your questions.